

# “High Throughput” Exploration of Oxide MBE Growth Space through Cyclical *in situ* Growth and Etching

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Beta phase gallium oxide ( $\beta$ -Ga<sub>2</sub>O<sub>3</sub>) is an emerging ultra-wide bandgap semiconductor that has attracted attention for its potential to outperform existing materials operating at high breakdown voltages and high temperature. Alloying of In and Al in  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> provides the ability to individually engineer the bandgap and lattice parameters of the material, providing a useful toolbox for heterostructure engineering. However, the tendency of (Al,In,Ga)<sub>2</sub>O<sub>3</sub> alloys to form competing phases, along with the complex suboxide chemistry of Ga and In, results in a growth window that is difficult to map and an alloy which is difficult to control.

We report on a high-throughput molecular beam epitaxy (MBE) technique to screen the growth conditions for the ternary alloy (In<sub>y</sub>Ga<sub>1-y</sub>)<sub>2</sub>O<sub>3</sub>, and the application of these findings to the successful synthesis of monoclinic (Al<sub>x</sub>Ga<sub>1-x-y</sub>In<sub>y</sub>)<sub>2</sub>O<sub>3</sub>. By leveraging the sub-oxide chemistry of Ga<sub>2</sub>O<sub>3</sub> and *in-situ* monitoring by reflection high-energy electron diffraction (RHEED), a cyclical growth and etch-back method is developed to rapidly characterize the (In<sub>y</sub>Ga<sub>1-y</sub>)<sub>2</sub>O<sub>3</sub> growth space. This cyclical method provides approximately 10x increase in experimental throughput and 46x improvement in Ga<sub>2</sub>O<sub>3</sub> substrate utilization. Growth conditions for monoclinic (In<sub>y</sub>Ga<sub>1-y</sub>)<sub>2</sub>O<sub>3</sub> are identified and targeted growths are characterized *ex-situ* to confirm improved In incorporation. These conditions are then used to grow quaternary (Al<sub>x</sub>Ga<sub>1-x-y</sub>In<sub>y</sub>)<sub>2</sub>O<sub>3</sub> with Al cation composition  $x$  ranging from 1% – 24% and In cation composition  $y$  ranging from 3% to 16%. The structural, chemical and optical properties of the alloys are investigated. An (Al<sub>0.17</sub>Ga<sub>0.76</sub>In<sub>0.07</sub>)<sub>2</sub>O<sub>3</sub> alloy lattice-matched to Ga<sub>2</sub>O<sub>3</sub> is examined by high resolution microscopy, highlighting the correlation between surface facets and composition. Such lattice-matched material can be grown arbitrarily thick without elastic strain and relaxation, making it suitable for high voltage diodes, transistor barriers, and epitaxial dielectrics.

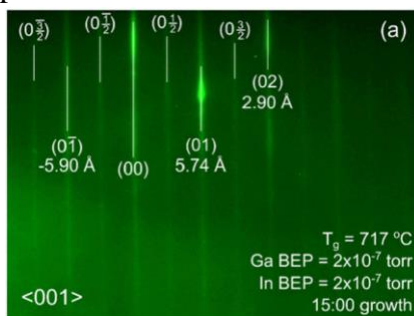


Figure 1: RHEED image typical of In-catalyzed Ga<sub>2</sub>O<sub>3</sub> growth

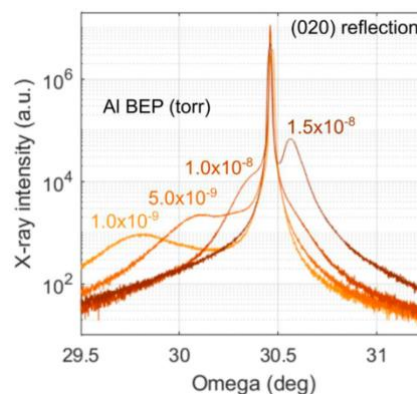


Figure 2: X-ray diffraction of (Al,In,Ga)<sub>2</sub>O<sub>3</sub> alloys grown at various Al flux values.

[1] S. Schaefer, J. Mater. Chem. A, **12**, 5508(2024).

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## Supplementary Pages (Optional)

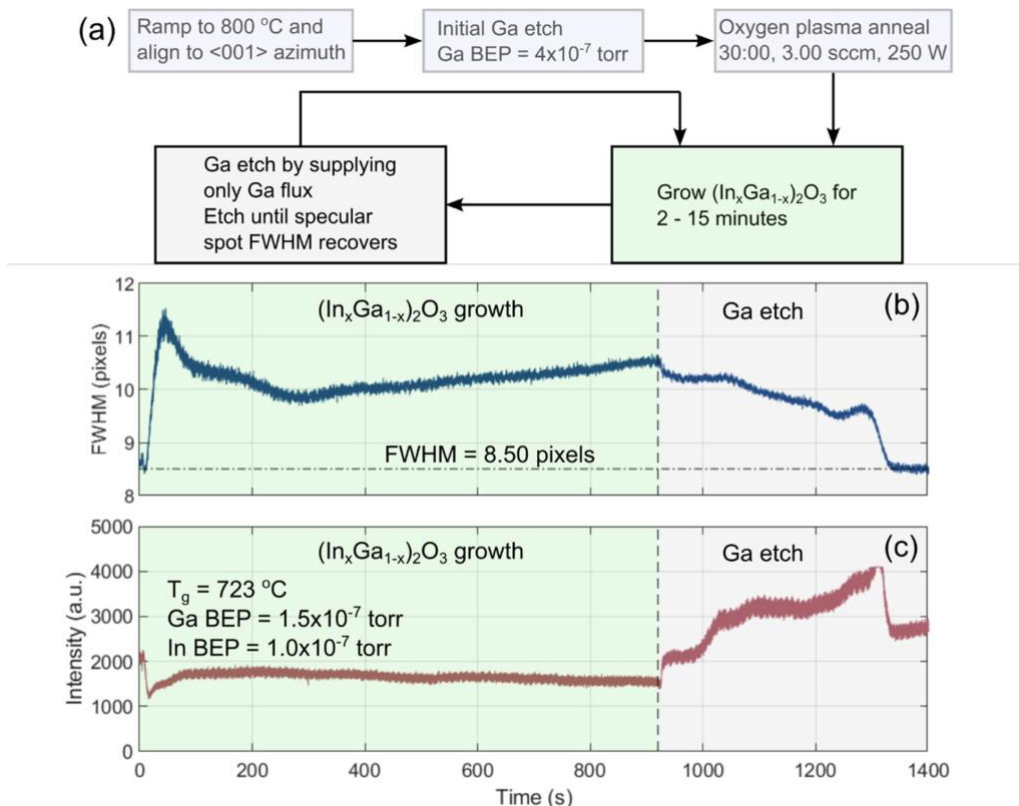


Figure S1: Overview of cyclical growth and etch process. (a) Flow diagram showing process of growth and etching. (b) FWHM of the specular RHEED reflection during the growth and etch-back process. (c) RHEED spot intensity during the growth and etch-back process.

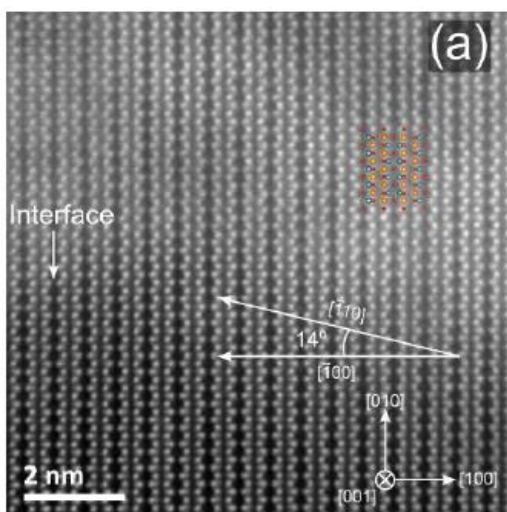


Figure S2: Scanning transmission electron microscopy (STEM) demonstrating beta phase  $(\text{Al}_{0.17}\text{Ga}_{0.76}\text{In}_{0.07})_2\text{O}_3$

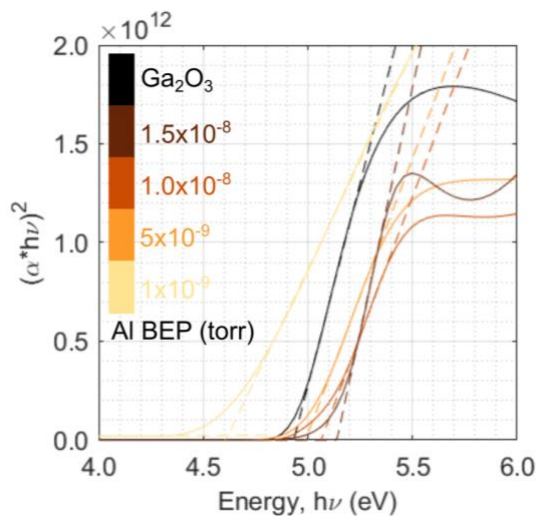


Figure S3: Spectroscopic ellipsometry Tauc analysis of  $(\text{Al},\text{In},\text{Ga})_2\text{O}_3$  optical absorption onset.